

M.E. ELECTRONICS AND TELE-COMMUNICATION ENGINEERING FIRST YEAR FIRST SEMESTER - 2025**Subject : SEMICONDUCTOR DEVICE PHYSICS AND MODELING Time : 3 hours Full Marks : 100**

Instructions : Answer all parts of a question together

Answer any six questions from 1 to 9 and Q10 [6×15+10=100]

1. a) Explain the family of cubic lattice alongwith its configurations with the help of diagrams. [10]
b) Find the Miller indices for a plane that intercepts the crystallographic axes at a , $2b$, and $3c$ in a cubic crystal system. [5]
 2. a) Explain the process of doping in semiconductor. Find the position of Fermi level for a silicon doped by 10^{16} donor atoms/cc. [8+2]
b) Draw and label a energy band diagram of a pn junction. [5]
 3. a) Find the expression for intrinsic carrier concentration. The number of available electronic states per unit volume per unit energy is given by: $g_c(E) = \frac{8\pi\sqrt{2}m_n^{3/2}}{h^3}(E - E_c)^{1/2}$ [10]
b) Given that N_C (Effective Density of States in the Conduction Band) is 10^{19} /cc. Calculate the intrinsic carrier concentration in Silicon. [5]
 4. a) How does temperature affect the mobility of electrons and holes? [5]
b) Derive the equation of current density for both drift and diffusion components. [10]
 5. Find the expression for total current of a p-n junction. [15]
 6. a) Explain Fermi level pinning. [5]
b) Draw energy band diagram of Schottky contact in n-type semiconductor showing schottky barrier height and built in potential clearly. Given Metal work function: $\Phi_M=4.9$ eV, Electron affinity of silicon: $\chi=4.1$ eV, Bandgap of silicon: $E_g=1.12$ eV, Doping concentration: $N_d=10^{16}$ cm $^{-3}$. [10]
 7. a) Explain the ideal MOS C-V curve at Low-Frequency (LFCV) and High-Frequency (HFCV) characteristics. [10]
b) Find the threshold Voltage for an n-channel MOS having following parameters: oxide thickness: $t_{ox}=5$ nm, oxide permittivity: $\epsilon_{ox}=3.9\epsilon_0$, silicon permittivity: $\epsilon_s=11.7\epsilon_0$, doping concentration: $N_A=10^{17}$ cm $^{-3}$, intrinsic carrier concentration: $n_i=1.5\times 10^{10}$ cm $^{-3}$ and work function difference between metal and semiconductor: $\Phi_{MS}=0.5$ V. [5]
 8. a) Describe the different types of oxide charges and their effect in MOS capacitor. [8]
b) Draw the energy band diagram of a MOS structure with $\Phi_M < \Phi_S$. [7]
 9. Explain the short-channel MOSFET effects, focusing on: a) Threshold voltage change with channel length scaling b) Drain Induced Barrier Lowering (DIBL) and c) Velocity saturation. [15]
 10. Derive the simplified I-V equation for a long-channel MOSFET in linear and saturation regions. [10]
- OR
- Describe the steps to find output and transfer characteristics of MOSFET using TCAD. [10]